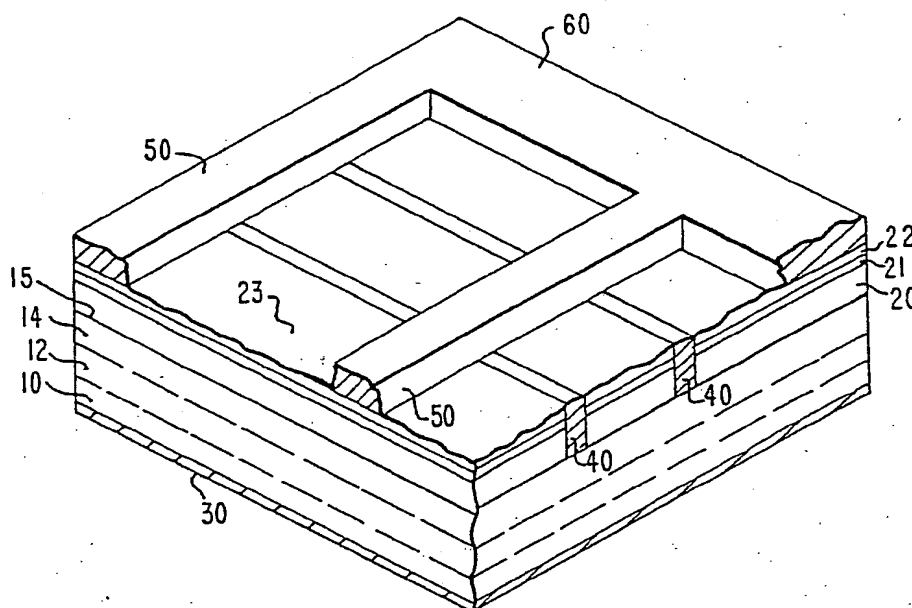




## INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

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**(54) Title:** SOLAR CELL HAVING IMPROVED FRONT SURFACE METALLIZATION

**(57) Abstract**

A gallium arsenide solar cell (6) having an aluminum gallium arsenide window layer (20) in which fine metallic contact lines (40) extend through the aluminum gallium arsenide window (20) to electrically contact the emitter layer (14), and a plurality of metallic grid lines (50) disposed on the window layer (23) cross the contact lines, thereby making electrical contact to the metallic contact lines (40). A flat metallic strip (60) extending along one of the edges of the solar cell electrically couples the grid lines (50) to one another. Consequently, two separate metals can be used, one with good ohmic contact properties for the metallic contact lines (40) and another with good adhesion and current conducting properties for the metallic grid lines (50). Additionally, the metallic contact lines (46) can be made very narrow to reduce the contact area to the emitter (14) thereby reducing the recombination current in the emitter.

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SOLAR CELL HAVING IMPROVED  
FRONT SURFACE METALLIZATION

BACKGROUND OF THE INVENTION

1 1. Field of the Invention

The present invention relates in general to solar cells, and more particularly, to solar cells having improved front surface metallization.

5 2. Description of Related Art

Conventional solar cells consist of a semiconductor body having a P-type conductivity layer, an N-type conductivity layer, an N-P or P-N semiconductor junction between these layers, a front light-receiving major surface and a back major surface. The layer adjacent the front surface is called the emitter, and the layer adjacent the back surface is called the buffer. When light energy impinges on the front light-receiving surface of the cell, electrons and corresponding holes are created in both the emitter and buffer. For the most part, because of the presence of the semiconductor junction, electrons will be directed toward one major surface of the cell and holes toward the other major surface, resulting in a photocurrent density. In a typical P-N gallium arsenide semiconductor junction solar cell, holes move to the front light receiving surface of the cell and electrons toward the back surface. Electrical contacts are attached to the front and back surfaces of the gallium arsenide semiconductor body

1 to collect the charge carriers. The electrons are  
collected by the back electrical contact and holes by  
the front electrical contact. The object is to collect  
as many electrons and holes as possible before they  
5 recombine, to attain the highest photo-current density  
possible.

A portion of the carriers directed toward the  
front surface, however, recombine under the front contact  
and thus do not contribute to the photo-current density.  
10 This is known in the art as the front surface recombination  
velocity. The front electrical contact of a gallium  
arsenide solar cell is one area where cell improvement  
has been sought by industry.

15 SUMMARY OF THE INVENTION

It is, therefore, an object of this invention to  
provide a solar cell in which front surface emitter  
recombination current is minimized.

It is a further object of this invention to pro-  
20 vide a solar cell with improved open circuit voltage  
and efficiency.

It is still a further object of this invention to  
provide a solar cell which can be reproducably manu-  
factured with high yield.

25 In accordance with the foregoing objects, a  
solar cell according to the present invention includes  
a semiconductor body having at least two adjacent  
impurity doped semiconductor layers of opposite conduc-  
tivity type forming the base and emitter layers of  
30 the solar cell respectively, with a semiconductor  
junction therebetween. The base and emitter layers  
have back and front major essentially parallel surfaces,  
respectively. A layer of aluminum gallium arsenide  
is disposed over the emitter layer front major surface  
35 and has an exposed major surface. The aluminum gallium

1 arsenide layer has a plurality of transverse grooves  
therein that extend vertically through this layer to  
the emitter layer front major surface. The grooves  
contain metal contact lines that electrically contact  
5 the emitter layer for charge carrier collection.  
A plurality of current collecting metallic grid lines  
located on the exposed front major surface cross the  
metallic contact lines making electrical contact to these  
contact lines. A flat metal strip also located on the  
10 aluminum gallium arsenide exposed major surface elec-  
trically couples the current collecting metallic grid  
lines to one another and provides a region for welding  
interconnection to other solar cells.

Other and further objects, advantages, and  
15 characteristic features of the present invention will  
become apparent from the following detailed description  
of preferred embodiment of the invention when taken in  
conjunction with the appended drawings.

20 BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1(a) is a plan view of a portion of a solar  
cell according to the principles of the invention;

FIG. 1(b) is a cross-sectional view taken along  
line b-b of FIG. 1(a);

25 FIG. 2 is a perspective view partly in section of  
a portion of a solar cell shown in FIG. 1a;

FIG. 3 is a plan view of a portion of a solar  
cell in accordance with another embodiment of the inven-  
tion;

30 FIG. 4 is a plan view of a solar cell in accor-  
dance with the invention.

FIGS. 5(a)-(g) are respective cross-sectional views  
(FIG. 5(g) also being in perspective) of a preferred method  
of fabricating a solar cell according to the invention.

1           DESCRIPTION OF THE PREFERRED EMBODIMENTS

Referring now, with greater particularity, to  
FIGS. 1a, 1b, and 2, a solar cell 6 is shown having a  
semiconductor body 7 with front and back major para-  
5    llel surfaces 8 and 9. The semiconductor body includes  
a substrate layer 10 which may be gallium arsenide,  
although germanium or silicon may be used instead.  
The substrate layer 10 may be impurity doped to an N+  
conductivity, for example. A buffer layer 12 overlies  
10   substrate 10 and is typically gallium arsenide which  
may be impurity doped to an N type conductivity, for  
example. If the substrate layer 10 is made of silicon  
semiconductor material, a layer of germanium is disposed  
between the substrate 10 and the gallium arsenide  
15   buffer 12 to lattice match the silicon semiconductor  
material to the gallium arsenide semiconductor material.  
An emitter layer 14 of gallium arsenide semiconductor  
material overlies the buffer layer 12 and may be of a  
P-type conductivity. An N-P junction 13 lies between  
20   the emitter layer 14 and the buffer layer 12. Overlying  
the emitter layer 14 is an aluminum gallium arsenide  
window layer 20 which is of the same conductivity  
type as the emitter layer 14, i.e., P-type conductivity.

Although an N-P semiconductor body is illustrated  
25   in FIG. 1b, a P-N semiconductor body may also be used  
where the substrate 10 is of P+ conductivity, the  
buffer layer 12 is of P conductivity, the emitter layer 14  
is of N conductivity, and the window layer 20 is of N con-  
ductivity.

30           Two antireflection coatings 21 and 22 overlie the  
front major surface 8 of the aluminum gallium arsenide  
window layer 20. The top antireflection coating 22 has an  
exposed major surface 23, and may be aluminum oxide,

1 and the bottom antireflection coating 21 may be titanium dioxide, for example. While two layers are typically used, fewer or more layers may be used. If a single layer is employed, it may be either silicon monoxide or  
5 tantalum oxide, for example.

A back contact 30 is located on the back major surface 9 of the semiconductor body 7. The back contact may cover the entire back surface of the solar cell or may be gridded.

10 A plurality of essentially parallel metallic contact lines 40 traverse the extent of the exposed major surface 23 of the cell. The metallic contact lines 40 typically have a rectangular cross-section and extend through the two anti-reflection coatings 21 and 22,  
15 and the aluminum gallium arsenide layer 20, to make contact to front major surface 15 of the emitter layer 14. The metallic contact lines 40 may be about 5 to 10 microns wide, for example. Narrower contact lines provide less contact area to the emitter layers lowering the emitter  
20 recombination current under the contacts by reducing the amount of emitter material exposed to a high recombination velocity region. Alternatively, instead of the contact lines 40 of FIG. 1, a plurality of metal rectangular contact segments 41 arranged in rows and columns, may  
25 be provided, as shown in FIG. 3, which further reduce the contact area to the emitter. Adjacent metal contact lines 40 or segments 41 may be spaced about 800 microns apart.

Current collecting metallic grid lines 50 disposed  
30 on the exposed major surface 23 of the top anti-reflection coating 22 longitudinally traverse the extent of the cell 6 generally perpendicular to the metallic contact lines 40. The metallic grid lines 50 cross and make electrical contact with the metallic contact  
35 lines 40. The width of the grid lines 50 may be about 25 to 60 microns, for example, but 30 to 40 microns

1 provides good results. Adjacent grid lines may be  
spaced apart by a distance of one to two millimeters,  
(one-half to one millimeters for FIG. 3) for example.  
The optimal spacing between adjacent grid lines 50,  
5 however, varies with the width selected for the metal  
contact lines 40, and the width and height of grid  
lines 50.

A flat metal strip 60 transversingly extends across  
the cell and is located on the exposed major surface  
10 23 of the top anti-reflection coating 22 near an edge  
of the cell 6. The strip 60 is essentially parallel  
to the metallic contact lines 40 and substantially  
perpendicular to the current collecting metallic grid  
lines 50, being intersected by and in electrical  
15 contact with grid lines 50. The flat metallic strip  
60 may have a rectangular surface area, or as shown in  
FIG. 4, may instead be in the form of a very narrow  
metallic strip 61 with one or more extended metallic  
regions 62 along the length of the strip 61. The  
20 extended regions 62 have sufficient surface area to  
weld to electrical interconnections from other  
cells.

A solar cell 6 is described above in which the con-  
tact resistance to the solar cell and the adhesion of  
25 the front electrical contacts to the solar cell can be  
individually optimized, and the contact area of the  
front surface metalization minimized. A metal alloy  
can be selected for the metal contact lines 40 that  
provides good electrical contact to the emitter layer  
30 14, thereby lowering contact resistance and increasing  
efficiency. A different metal alloy can be selected  
for the current collecting metallic grid lines 50 and  
the flat metallic strip 60 that provides good adhesion  
to the cells' exposed major face 23, thereby maximizing  
35 the mechanical integrity of the flat metallic strip 60  
and the grid lines 50. Additionally, the metallic



1 contact lines 40 can be made very narrow, i.e., in the  
range of 5 to 10 microns compared to 50 to 60 microns  
for typical prior art cells. Consequently, the contact  
area of the metallic contact lines 40 to the emitter  
5 layer 14 of the cell may be greatly reduced lowering  
the recombination current at the emitter front major  
surface, and thereby increasing voltage and efficiency.  
Moreover, solar cells embodying the invention  
may be fabricated by relatively low cost, high yield  
10 processes.

The fabrication of the semiconductor body 7 has  
been described in several publications in the past  
such as G. S. Kamath, Advanced Solar Cells for Space  
Applications, Proceedings of 21st IECEC 1425-26  
15 (Aug 1986) which is incorporated herein by reference.  
Briefly, however, as shown in FIG. 5a, a layer of  
N-type conductivity gallium arsenide 12, the base, is  
grown on top of a N+ gallium arsenide substrate 10  
using any one of many well known techniques, one of  
20 which is liquid phase epitaxy. The N-type base layer  
12 typically has a concentration of about  $2 \times 10^{17}$   
impurity atoms per cubic centimeter and a thickness of  
about 10 microns, while the N+ substrate layer 10  
typically has a concentration of about  $2 \times 10^{18}$   
25 impurity atoms per cubic centimeter and a thickness of  
250 microns.

In the next processing step shown in FIG. 5b, an  
aluminum gallium arsenide layer 20 is grown on top of  
the N layer 12 by liquid phase epitaxy, metal organic  
30 chemical vapor deposition, molecular beam epitaxy, for  
example. The aluminum gallium arsenide is doped with a  
P-type dopant which may be beryllium of a typical  
concentration of  $2 \times 10^{18}$  atoms per cubic centimeter,

1 for example. Upon deposition of the aluminum gallium  
arsenide layer 20, beryllium atoms from this layer  
diffuse into the N layer 12 thereby doping a thin  
emitter layer 14 adjacent the aluminum gallium arsenide  
5 layer 20 to P-type conductivity. The aluminum gallium  
arsenide layer 20 typically contains about  $2 \times 10^{18}$   
impurity atoms and is grown to a thickness of about  
0.03.-0.4 microns.

After the semiconductor body 7 has been fabricated,  
10 two anti-reflection coatings 21 and 22 typically of  
aluminum oxide and titanium oxide, respectively, may be  
deposited on the aluminum gallium arsenide layer 20,  
by any technique known in the art, shown in FIG. 5c.  
However, additional or fewer layers of antireflection  
15 coatings may be employed. Reference may be made to F.  
Bunshah et al, Deposition Technology for Films and  
Coatings (Noyes Publ. 1982) which is incorporated  
herein by reference.

Thereafter, as shown in FIG. 5d, the back surface  
20 metallization 30 is applied. A metal alloy, such as gold,  
germanium, and nickel, for example, is electron beam  
evaporated or otherwise deposited over the back major  
surface 9, and thereafter sintered to form good ohmic  
contact to the semiconductor body 7. The back surface  
25 metallization may precede the deposition of the anti-  
reflection coatings without affecting the properties of  
the cell.

In the next step, the metal contact lines 40 are  
fabricated onto the solar cell semiconductor body.  
30 The exposed major surface 23 of layer 22 is provided  
with a patterned layer of photoresist (not shown), and  
the exposed portions are etched vertically through the  
two antireflection coatings 21 and 22 and the aluminum  
gallium arsenide window layer 20 to the emitter layer  
35 14 front major surface 15, forming fine grooves 42, as

1 shown in FIG. 5e. Thereafter a metal alloy, such as  
gold and zinc, for example, is sputtered over the  
photoresist and into the fine grooves 42, and then  
silver is evaporated thereon using electron vacuum  
5 deposition. Alternatively, the metallic contact  
lines 40 may be deposited on the exposed major surface  
23 using ion plating, evaporation from a resistive  
source, or electroplating. The remaining photoresist  
is thereafter lifted off along with the metal on the  
10 photoresist using organic solvents leaving behind the  
fine metallic contact lines 40, as shown in FIG 5f.

After the metallic contact lines 40 have been  
deposited, the metallic grid lines 50 and the flat  
metallic strip 60 are fabricated onto the cell, as shown  
15 by FIG. 5g. Using mechanical foil mask processing, a  
foil mask, with openings for the grid lines and flat  
strip is placed on the exposed major surface 23  
of the top anti-reflection coating 22, and metal is  
evaporated onto the surface. The metal is thereafter  
20 sintered to provide good adhesion to the top anti-re-  
flection coated exposed major surface 23. A metal  
alloy such as titanium, gold, zinc, and silver may be  
used, for example, which provides good adhesion.

It will be appreciated that while the embodiment  
25 of the solar cell structure illustrated herein employs  
an P-N semiconductor body 7, the principles of the  
invention are also applicable to N-P type cells.

Thus, although the present invention has been  
shown and described with the reference to particular  
30 embodiments, nevertheless various changes and modif-  
ications obvious to one skilled in the art are deemed  
to be within the spirit, scope, and contemplation of  
the invention as set forth in the appended claims.

CLAIMSWhat is Claimed is:

1           1. A solar cell comprising:

          a body of semiconductor material having a  
first layer of a first conductivity type and a second  
layer of a second conductivity type opposite to said  
5 first conductivity type disposed adjacent to said first  
layer, said first and second layers having back  
and front major essentially parallel surfaces, respec-  
tively, and a semiconductor junction therebetween essen-  
tially parallel to said front and back surfaces;

10           a layer of aluminum gallium arsenide disposed  
on said front major surface and having an exposed  
front surface and a plurality of grooves therein  
extending vertically therethrough to said second layer;

          a plurality of metallic contact lines in said  
15 grooves making electrical contact to said second layer;

          a plurality of metallic grid lines on  
said aluminum gallium arsenide exposed front surface  
crossing said metallic contact lines and electrically  
contacting said metallic contact lines; and

20           a flat metallic strip disposed on said aluminum  
gallium arsenide layer exposed front surface electrically  
coupling said conductive bars to one another said flat  
metallic strip having sufficient surface area to weld  
interconnection from other solar cells.

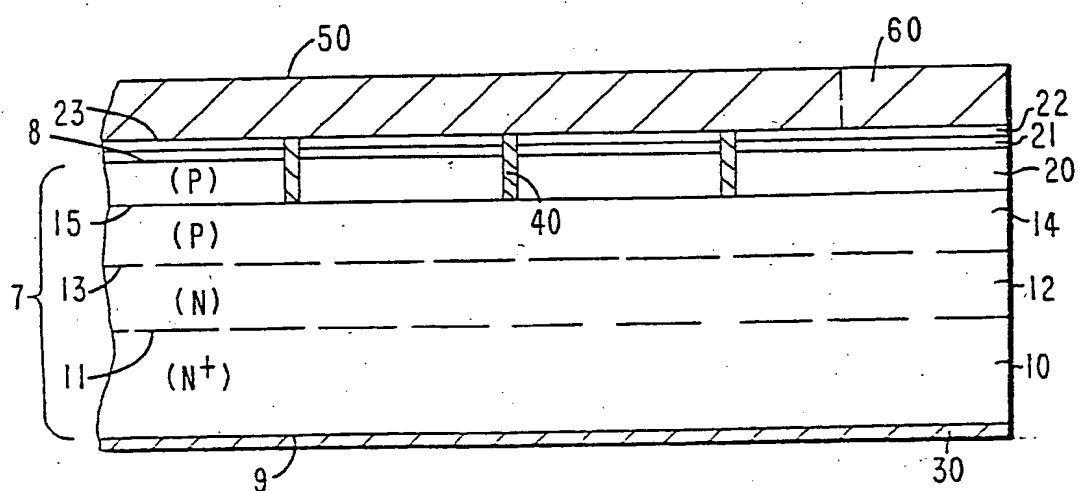
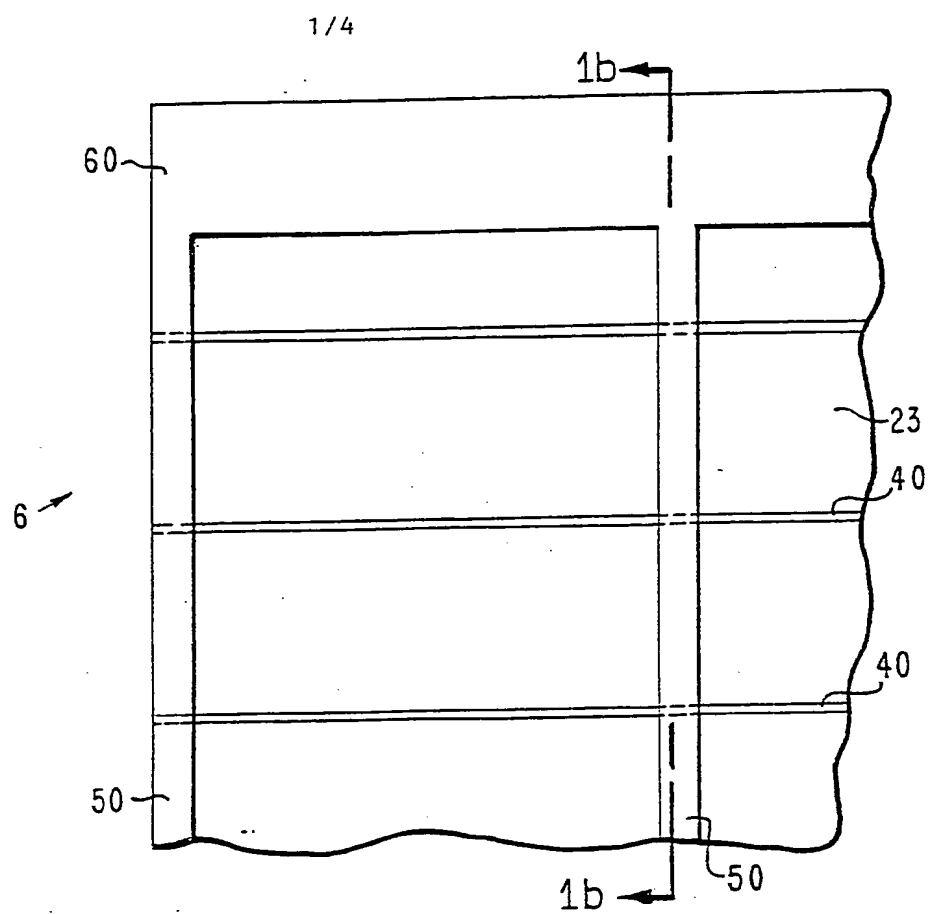
1           2. A solar cell as defined in Claim 1 wherein  
said semiconductor body is made of gallium arsenide,  
said first layer is of P conductivity type, said second  
layer is of N conductivity type, and said aluminum  
5 gallium arsenide layer is of N conductivity type.

1           3. A solar cell as defined in Claim 1 wherein  
said first layer is of P+ conductivity, said second  
layer is of P conductivity, and said third layer and  
said aluminum gallium arsenide layer is of N conduc-  
5   tivity.

1           4. A solar cell as defined in Claim 1 wherein  
said metallic contact lines are essentially parallel  
to one another.

1           5. A solar cell as defined in Claim 4 wherein said  
metallic grid lines are essentially parallel to one  
another and essentially perpendicular to said metallic  
contact lines.

1           6. A solar cell as defined in Claim 1 wherein  
said metallic contact lines are divided into a plurality  
of metallic rectangular contact segments arranged in rows  
and columns.



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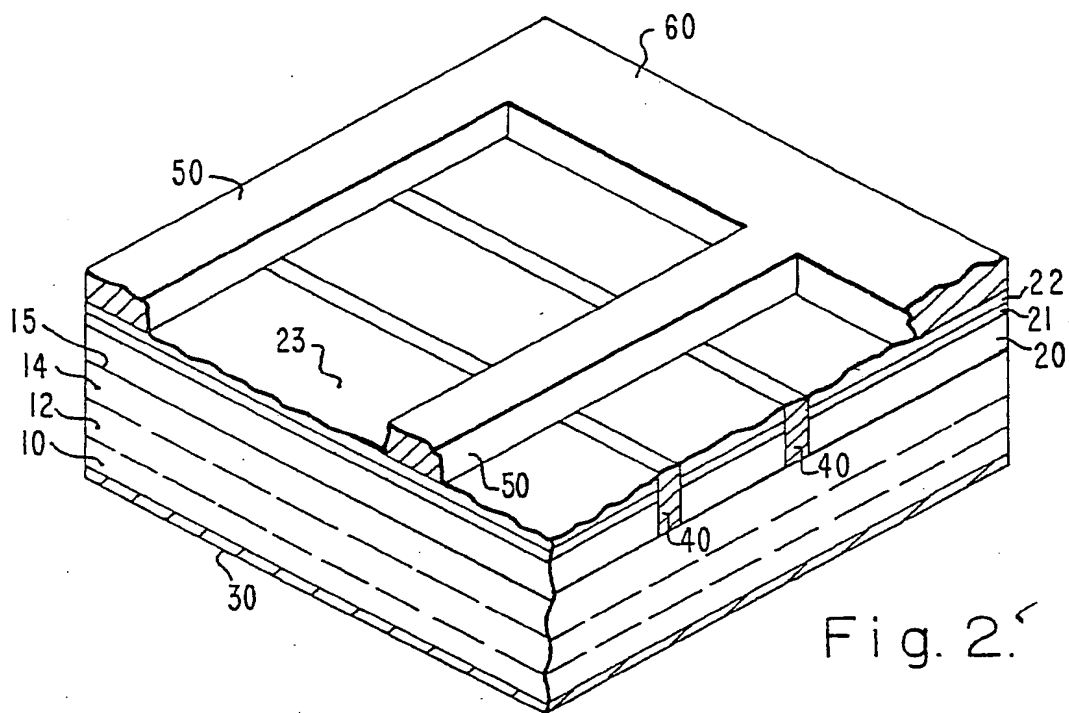


Fig. 2.

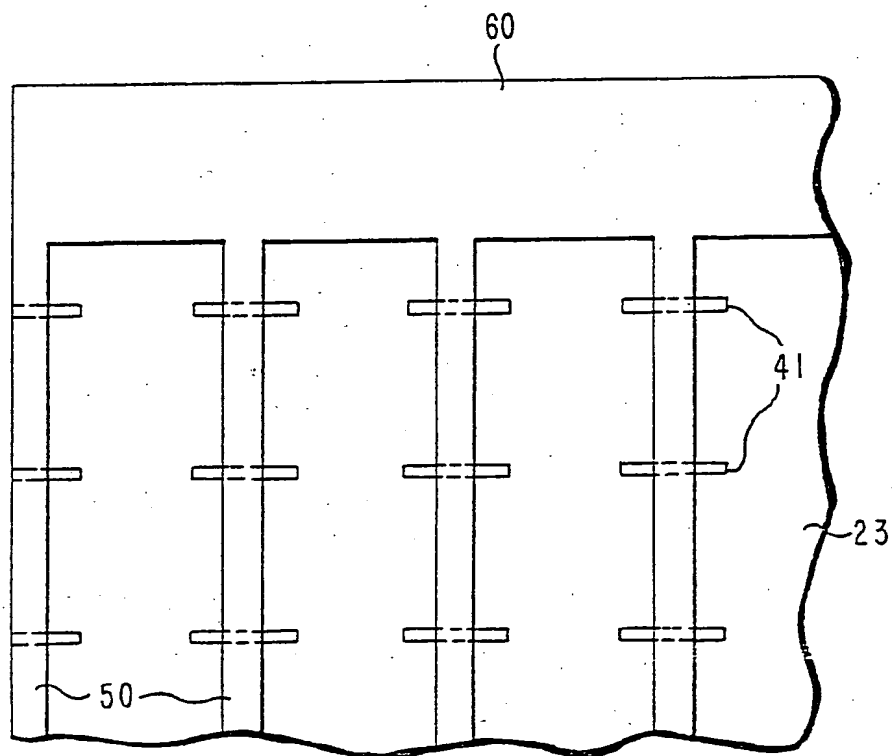


Fig. 3.

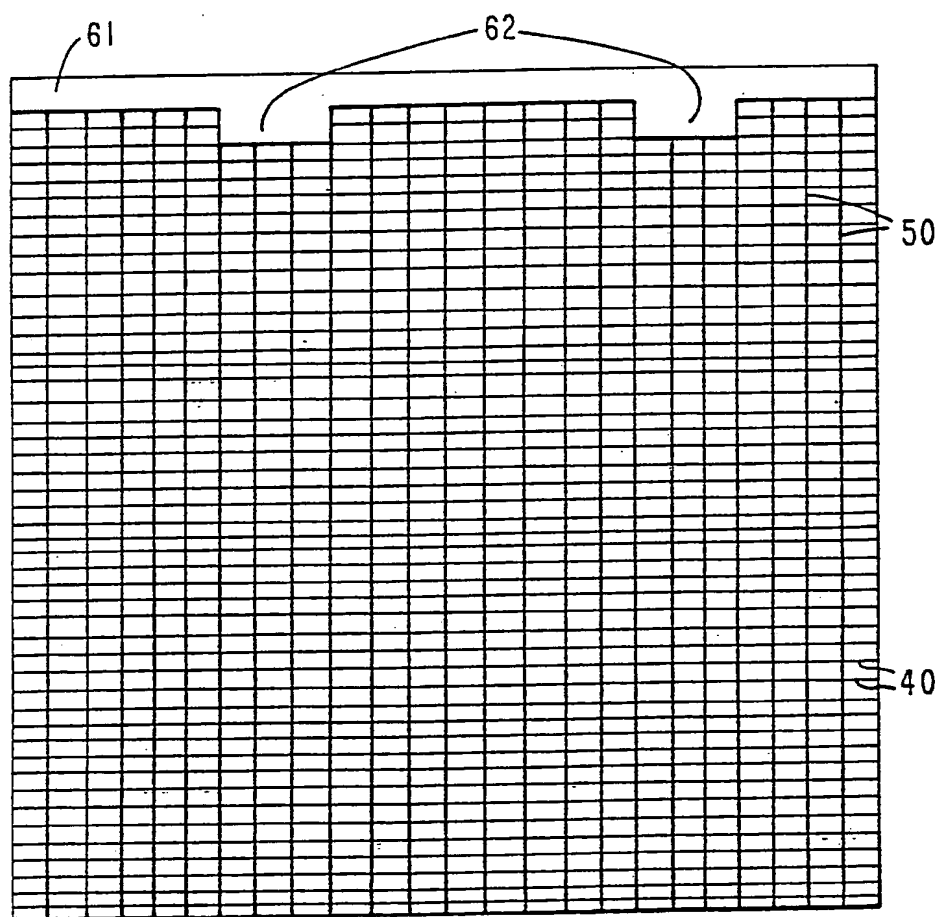


Fig. 4.



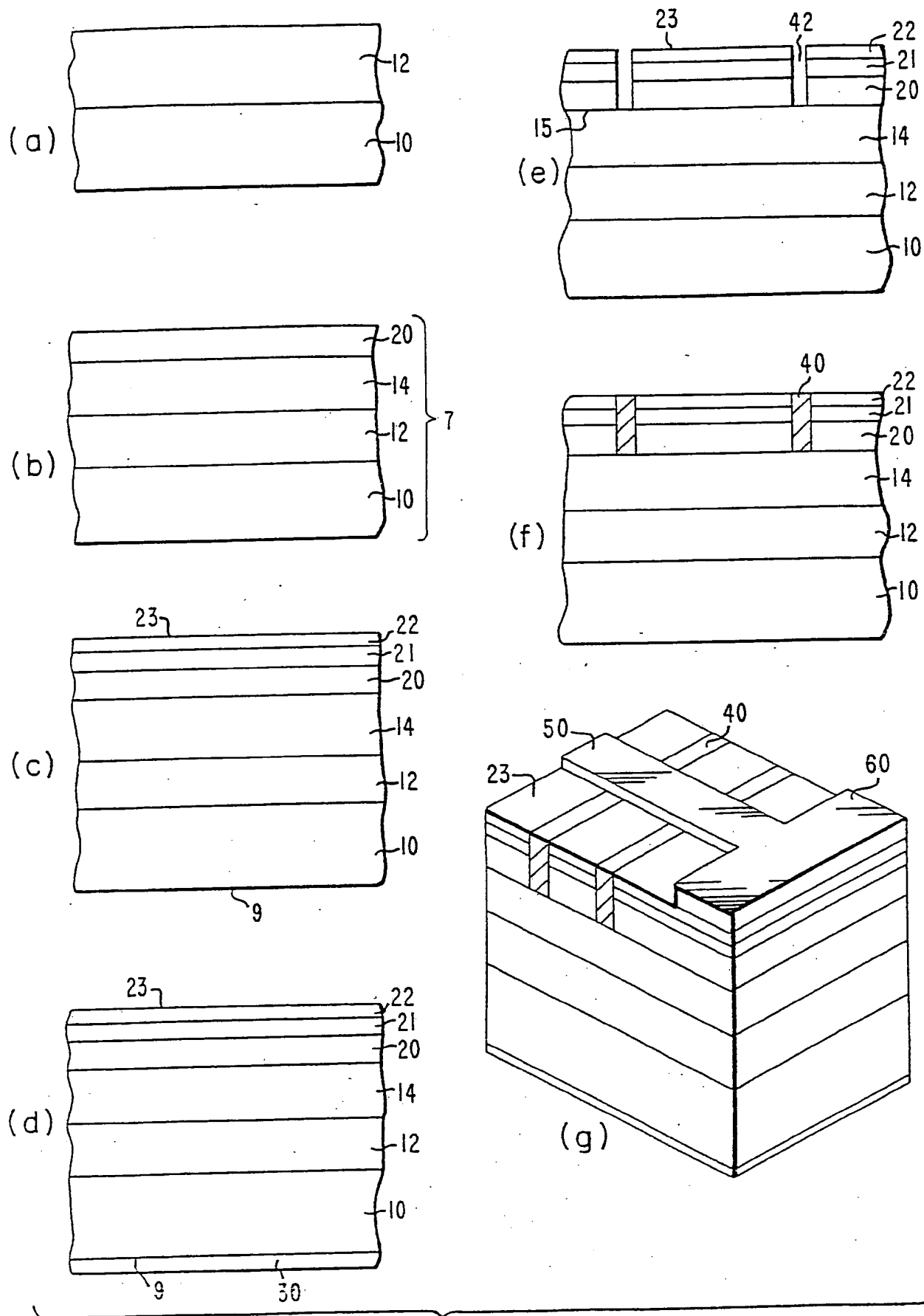


Fig. 5.

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